

Title (en)

Method for testing an exhaust gas recirculation system

Title (de)

Verfahren zur Überprüfung einer Abgasrückführanlage

Title (fr)

Procédé pour tester un système de recirculation de gaz d'échappement

Publication

**EP 1180594 A3 20030102 (DE)**

Application

**EP 01118459 A 20010731**

Priority

DE 10039952 A 20000816

Abstract (en)

[origin: EP1180594A2] Process for monitoring an exhaust gas in a recirculating device of an I.C. engine comprises adjusting a determined change of the exhaust gas recirculating rate; measuring the NO<sub>x</sub> concentration in the exhaust gas; and establishing a defect in the recirculating device from the concentration difference depending on the change of the exhaust gas recirculating rate. Preferred Features: The concentration difference from the NO<sub>x</sub> concentration measured before and after the change of the exhaust gas recirculating rate. The NO<sub>x</sub> concentration is measured downstream of a NO<sub>x</sub> storage catalyst and the catalyst is saturated to its maximum storage capability before adjusting the determined change of the exhaust gas recirculating rate. Saturation is recognized downstream of the catalyst. Monitoring is only carried out when the operating parameters of the engine lie within a determined region and/or have limited dynamics.

IPC 1-7

**F02M 25/07**

IPC 8 full level

**F02M 25/07** (2006.01); **F02M 26/46** (2016.01); **F02M 26/49** (2016.01)

CPC (source: EP US)

**F02M 26/46** (2016.02 - EP US); **F02M 26/49** (2016.02 - EP US); **F02D 41/0055** (2013.01 - EP US); **F02D 41/146** (2013.01 - EP US); **F02M 26/48** (2016.02 - EP US)

Citation (search report)

- [Y] PATENT ABSTRACTS OF JAPAN vol. 013, no. 060 (M - 796) 10 February 1989 (1989-02-10)
- [Y] PATENT ABSTRACTS OF JAPAN vol. 1998, no. 09 31 July 1998 (1998-07-31)
- [Y] PATENT ABSTRACTS OF JAPAN vol. 011, no. 392 (M - 653) 22 December 1987 (1987-12-22)
- [Y] PATENT ABSTRACTS OF JAPAN vol. 1998, no. 14 31 December 1998 (1998-12-31)
- [A] PATENT ABSTRACTS OF JAPAN vol. 017, no. 479 (M - 1471) 31 August 1993 (1993-08-31)
- [A] PATENT ABSTRACTS OF JAPAN vol. 1995, no. 11 26 December 1995 (1995-12-26)

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CN112539121A; CN114183260A

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**EP 1180594 A2 20020220**; **EP 1180594 A3 20030102**; **EP 1180594 B1 20060906**; DE 10039952 A1 20020228; DE 10039952 C2 20030424; DE 50110924 D1 20061019; US 2002033045 A1 20020321; US 6598470 B2 20030729

DOCDB simple family (application)

**EP 01118459 A 20010731**; DE 10039952 A 20000816; DE 50110924 T 20010731; US 92895801 A 20010813